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Docket No.: SON-2769
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Hidetoshi Ohnuma

Application No.: 10/603,689

Filed: June 26, 2003

Conf. No. 2872
Examiner: Saleha R. Mohamedulla

Group Art: 1756

For: EXPOSURE METHOD, MASK
FABRICATION METHOD, FABRICATION
METHOD OF SEMICONDUCTOR DEVICE,
AND EXPOSURE APPARATUS

STATUS INQUIRY

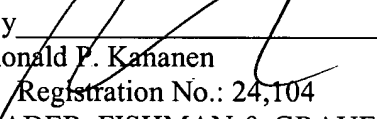
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Please advise us when an action on the merits may be expected from the Patent and Trademark Office. A Response to Election of Invention Requirement was filed on August 3, 2005.

Dated: February 9, 2006

Respectfully submitted,

By 
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